

### Claims

1. A method for the manufacture of rotationally symmetric quartz glass crucibles wherein an electric arc is produced by means of an electrode arrangement, thus a wall or a section of a wall of the simultaneously rotating quartz glass crucible being heated, **characterized in that** by at least one additional electrode arrangement, an additional section of the wall of the quartz glass crucible is heated.
2. A method according to Claim 1, **characterized in that** – due to the electrode arrangement – different sections are heated which are at a distance from each other in the direction of the rotational axis of the quartz glass crucible.
3. A device for the manufacture of a rotationally symmetrical quartz glass crucible through sectionally heating it by means of an electrode arrangement provided for the generation of an electric arc, comprising one or several anodes and one cathode, with the quartz glass crucible being rotatable around its axis of rotation, **characterized in that** the device (5) - in addition to the first electrode arrangement (7) – is provided with at least one additional electrode arrangement (8), consisting of one or several anodes (9) and one cathode (10), which is inclined towards a section (15) of the quartz glass crucible (2), such section facing away from the first electrode arrangement (7).
4. A device according to Claim 3, **characterized in that** the electrode arrangements (7, 8) are arranged in different positions which are at a distance from each other in the direction of the rotational axis (16) of the quartz glass crucible (2).
5. A device according to Claim 3 or 4, **characterized in that** the electrode arrangements (7, 8) can be moved independently of each other.

6. A device according to at least one of the Claims 3 to 6, **characterized in that** the electrode arrangements (7, 8) are arranged uniformly distributed with regard to the circumference of the quartz glass crucible (2).
7. A device according to at least one of the Claims 3 to 6, **characterized in that** at least one electrode arrangement (7, 8) is provided with a feed-in for SiO<sub>2</sub> grains, while at least one other electrode arrangement (7,8) is exclusively intended for heating.